

## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Toru YAMADA et al.

Application No.: 10/582,860

Filed: June 14, 2006

Docket No.: 136164

For:

VAPOR PHASE GROWTH APPARATUS AND METHOD OF FABRICATING

EPITAXIAL WAFER

## **NOTICE OF CHANGE OF ADDRESS**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please address all future communications in connection with the aboveidentified application to:

## OLIFF & BERRIDGE, PLC CUSTOMER NUMBER 25944

Respectfully submitted,

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RRS/tbm

Date: February 11, 2008

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